## The invention claimed is:

1. A foot-operated controller comprising:

a substrate having a plurality of pressure sensors mounted at selected locations on the substrate to facilitate control of a controllable electromechanical device by application of pressure from selected parts of a foot to the sensors; and

a microprocessor for receiving input from the sensors and converting the sensor inputs into commands for the controllable electromechanical device.

- 2. The foot-operated controller of claim 1, further comprising a radio transmitter for converting pressure exerted on the sensors by various parts of a foot into control signals that are broadcast to a receiver and transmitted to an electromechanical device.
- 3. The foot-operated controller of claim 1, located on or within the insole of a shoe.
- 4. The foot-operated controller of claim 1, in which the microprocessor is hard-wired to the controllable electromechanical device.
- 5. The foot-operated controller of claim 1, wherein the microprocessor is located on the substrate.
- 6. A prosthetic system comprising:
  - a prosthetic device;
- a foot-operated controller including a substrate having a plurality of pressure sensors mounted at selected locations on the substrate to facilitate control of the prosthetic device; and
- a microprocessor for receiving input from the sensors and converting the sensor inputs into commands for the prosthetic device.
- 7. The prosthetic system of claim 6, wherein the prosthetic device is a prosthetic hand.

- 8. The prosthetic system of claim 6, further comprising a radio transmitter for converting pressure exerted on the sensors by various parts of a foot into control signals that are broadcast to a receiver and transmitted to an electromechanical device.
- 9. The prosthetic system of claim 6, located on or within the insole of a shoe.
- 10. The prosthetic system of claim 6, in which the microprocessor is hard-wired to the controllable electromechanical device.
- 11. The prosthetic system of claim 6, wherein the microprocessor is located on the substrate.